

IN THE CLAIMS:

This listing of claims will replace all prior versions, and listings, of claims in the Application:

1. (Previously presented) A substrate holder comprising:
a fixed portion configured and operative to be attached to a precision stage;
a movable portion operably coupled to said fixed portion and selectively movable relative thereto;
a securing mechanism configured and operative to secure a substrate at a predetermined location relative to movable portion; and
an actuator mechanism operative to provide movement of said movable portion relative to said fixed portion, said movement being operative to position a selected area of said substrate within a precision travel range of said precision stage.
2. (Original) The substrate holder of claim 1 wherein said actuator mechanism is operative to translate said movable portion in one dimension relative to said fixed portion.
3. (Original) The substrate holder of claim 1 wherein said actuator mechanism is operative to translate said movable portion in two dimensions relative to said fixed portion.
4. (Original) The substrate holder of claim 1 wherein each of said fixed portion and said movable portion comprises a respective aperture cooperating to form a window in said holder, and wherein said securing mechanism is operative to secure the substrate at a selected location relative to the window.
5. (Original) The substrate holder of claim 1 further comprising an indexed reference system.
6. (Original) The substrate holder of claim 5 wherein said indexed reference system comprises:
a pointer; and
a plurality of reference indicia, each corresponding one of said plurality of reference indicia associated with a corresponding area of the substrate.
7. (Previously presented) The substrate holder of claim 6 wherein said indexed reference system is operably coupled to said actuator mechanism and wherein selective alignment of

ones of said plurality of reference indicia with said pointer translates the corresponding area of the substrate within said precision travel range .

8. (Original) The substrate holder of claim 1 wherein said actuator mechanism is motor driven.

9. (Previously presented) A precision travel staging system comprising:
a precision stage having a precision travel range;
a substrate holder having a fixed portion configured and operative to be attached to said stage, and a movable portion operably coupled to said fixed portion and selectively movable relative thereto;

a securing mechanism configured and operative to secure a substrate at a predetermined location relative to said movable portion of said substrate holder; and
an actuator mechanism operative to provide movement of said movable portion relative to said fixed portion, wherein the movement positions a selected area of said substrate within said precision travel range.

10. (Previously presented) A precision travel staging system comprising:
a precision stage;
a substrate holder having a fixed portion configured and operative to be attached to said stage, and a movable portion operably coupled to said fixed portion and selectively movable relative thereto;

a securing mechanism configured and operative to secure a substrate at a predetermined location relative to said movable portion of said substrate holder; and
an actuator mechanism operative to provide movement of said movable portion relative to said fixed portion,
wherein said fixed portion of said substrate holder is integrated with said stage.

11. (Previously presented) A precision travel staging system comprising:
a precision stage;
a substrate holder having a fixed portion configured and operative to be attached to said stage, and a movable portion operably coupled to said fixed portion and selectively movable relative thereto;

a securing mechanism configured and operative to secure a substrate at a predetermined location relative to said movable portion of said substrate holder; and

an actuator mechanism operative to provide movement of said movable portion relative to said fixed portion,

wherein a fixed position of said fixed portion of said substrate holder is selectively alterable relative to said stage.

12. (Original) The staging system of claim 9 wherein each of said fixed portion and said movable portion comprises a respective aperture cooperating to form a window in said substrate holder, and wherein said securing mechanism is operative to secure the substrate at a selected location relative to the window.

13. (Original) The staging system of claim 9 further comprising an indexed reference system.

14. (Original) The staging system of claim 13 wherein said indexed reference system comprises:

a pointer; and

a plurality of reference indicia, each corresponding one of said plurality of reference indicia associated with a corresponding area of the substrate.

15. (Previously presented) The staging system of claim 14 wherein said indexed reference system is operably coupled to said actuator mechanism and wherein selective alignment of ones of said plurality of reference indicia with said pointer translates the corresponding area of the substrate within said precision travel range .

16. (Original) The staging system of claim 9 wherein said actuator mechanism is motor driven.

17. (Previously presented) A method of selectively positioning a substrate in a limited travel staging system; said method comprising:

attaching a fixed portion of a substrate holder to a precision stage;

coupling a movable portion of the substrate holder to the fixed portion;

securing a substrate in a predetermined position relative to the movable portion; and

positioning a desired area of the substrate within a precision travel range of the stage.

18. (Original) The method of claim 17 wherein said securing comprises utilizing a spring biased element.

19. (Original) The method claim 17 further comprising indexing the substrate holder such that each of a plurality of reference indicia on an index is associated with a corresponding area of the substrate.
20. (Previously presented) The method of claim 19 wherein said indexing enables selective alignment of ones of said plurality of reference indicia with a pointer to translate a corresponding area of the substrate within the precision travel range .
21. (Previously presented) The method of claim 19 wherein said positioning includes selectively aligning one of said plurality of reference indicia with a pointer to translate a corresponding area of the substrate within the precision travel range.
22. (Previously presented) The method of claim 21 and further comprising repeating the step of positioning to sequentially translate selected areas of the substrate within the precision travel range.
23. (Previously presented) The substrate holder of claim 4 wherein said window corresponds to said precision travel range.
24. (Previously presented) The substrate holder of claim 4 wherein said window corresponds to said precision travel range.